

## Low Voltage Induced Reversible Magnetoelectric Coupling in Fe<sub>3</sub>O<sub>4</sub> Thin Films for Voltage Tunable Spintronic Devices

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## 1. XRD and HRTEM images

There are no other reflections in the Figure S1a could be seen in the whole range except the (200) and (400) peaks of the MgO substrate and (800) peak of Fe<sub>3</sub>O<sub>4</sub>, which indicates high-quality epitaxial growth of Fe<sub>3</sub>O<sub>4</sub> on MgO substrates. High resolution transmission electron microscopy (HRTEM) images with different scale showing sharp interface between the Fe<sub>3</sub>O<sub>4</sub> films and the MgO substrate are shown in b-e..

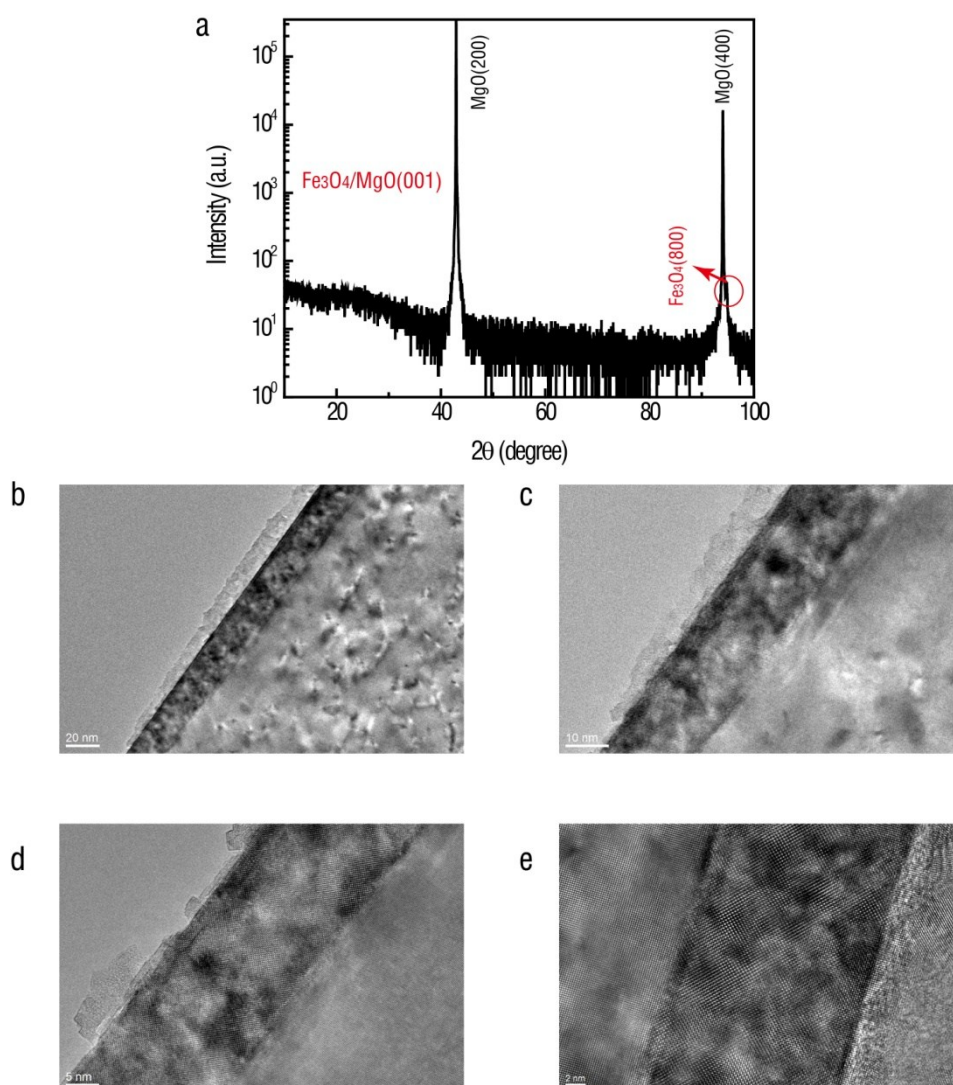


Figure S1(a) X-ray diffraction patterns of the Fe<sub>3</sub>O<sub>4</sub>/MgO heterostructure. (b-e)

Different scale HRTEM images at the interface

## 2. Out-of-plane VSM curves as a function of gating voltage.

Due to the VSM measurement take place in open environment, it is impossible to keep the same  $N_2$  atmosphere as the EPR test in a closed chamber. It can be seen from the inset in Figure S2 that the coercive field almost keeps constant and the saturation magnetization shows random variations. This is because that in air condition the charge doping and generation of oxygen vacancy especial the latter is different in  $N_2$  condition.

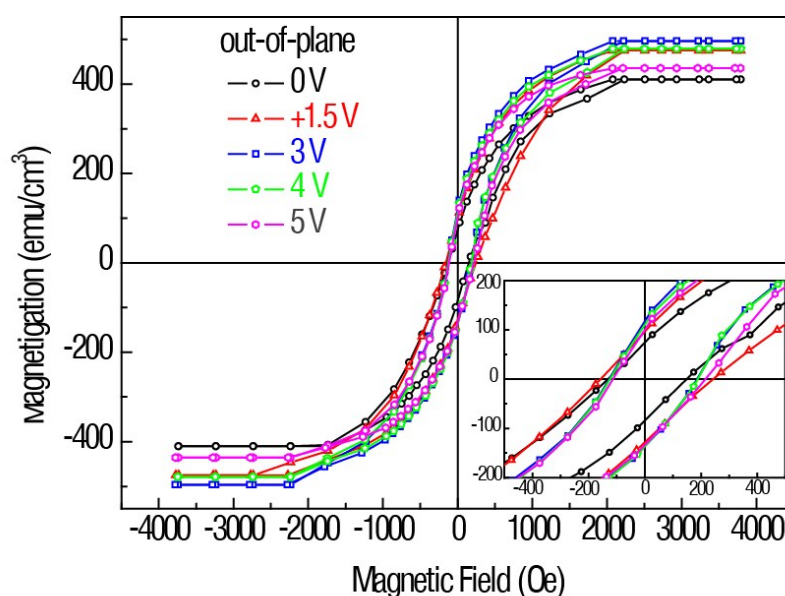


Figure S2 Out-of-plane of *in-situ* VSM test of the Au/[DEME]<sup>+</sup>[TFSI]<sup>-</sup>/Fe<sub>3</sub>O<sub>4</sub>/MgO heterostructure at different V<sub>g</sub>. The inset shows the local image near the zero magnetic field

## 3. Angular dependence of H<sub>r</sub> results

H<sub>r</sub> increased as a function of V<sub>g</sub> (angle < 60°) while the H<sub>r</sub> decreased for angle > 60°. It was found that the magnetic easy axis is in the film plane (in-plane) and the hard axis is perpendicular to the film (out-of-plane). The maximum H<sub>r</sub> shift was obtained along out-of-plane direction with 280 Oe tunability. Since the greatest

tunability was obtained in this direction, the following reversible test was performed along out-of-plane.

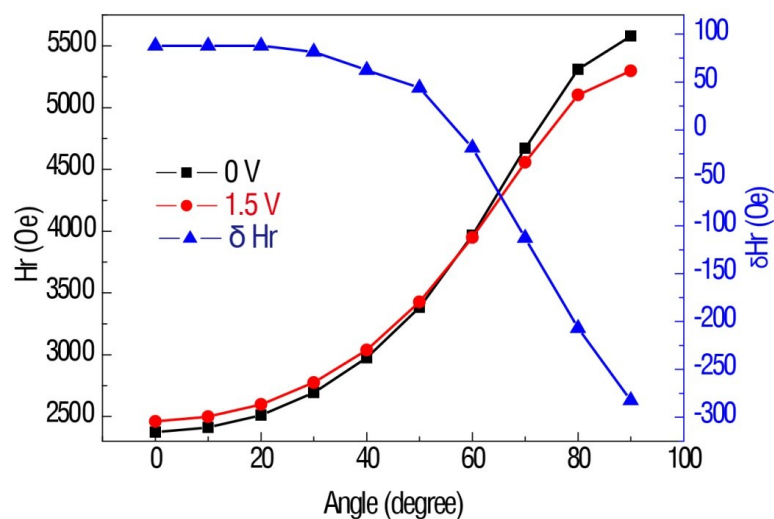


Figure S3 Angular dependence of  $H_r$  under 0 V (black square line) and 1.5 V (red circle line), respectively, the triangle line presents the E-field induced  $H_r$  shift as a function of the angle. The in-plane direction was defined as  $0^\circ$  and the out-of-plane was defined as  $90^\circ$ .

#### 4 EPR data of reversible test

To verify the stability of the IL gating control of magnetism, out-of-plane  $H_r$  shift of  $\text{Fe}_3\text{O}_4/\text{MgO}$  heterostructure as a function of  $\pm 1.5 \text{ V } V_g$  was tested for circles. It is important to obtain normal EPR data for identifying the  $H_r$  shift. In Figure S4, the contour map of the out-of-plane FMR spectra for one cycle and 80 cycles were given, showing great tunability and reversibility. Also the four representative EPR data from the first test to the eightieth time were shown, from which we can obtain a stable and reversible EPR signal even after dozens of test.

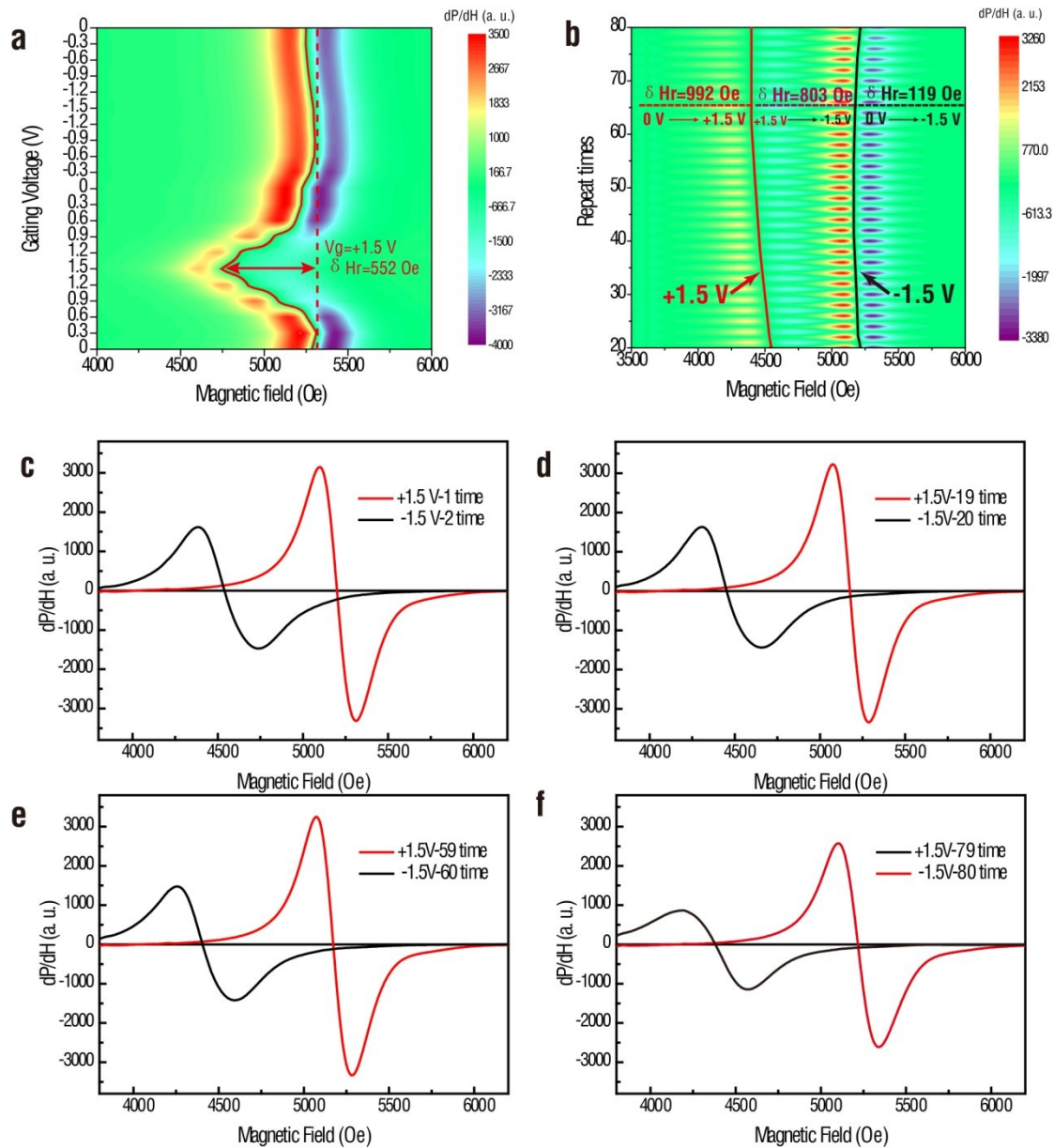


Figure S4a The contour map of the out-of-plane FMR spectra for one cycle. The gating process was the same as that shown in Figure 3(a) in the manuscript. b. the contour map of the out-of-plane FMR spectra for 80 cycles. (c) to (f) the red line and black line represent the  $H_r$  at  $V_g = +1.5$  V and  $-1.5$  V, respectively. Figure S3 Representative EPR data of the repeated test

## 5. Fitting of the measured XRR profile for the ungated, 1.5 V and 5 V gated samples

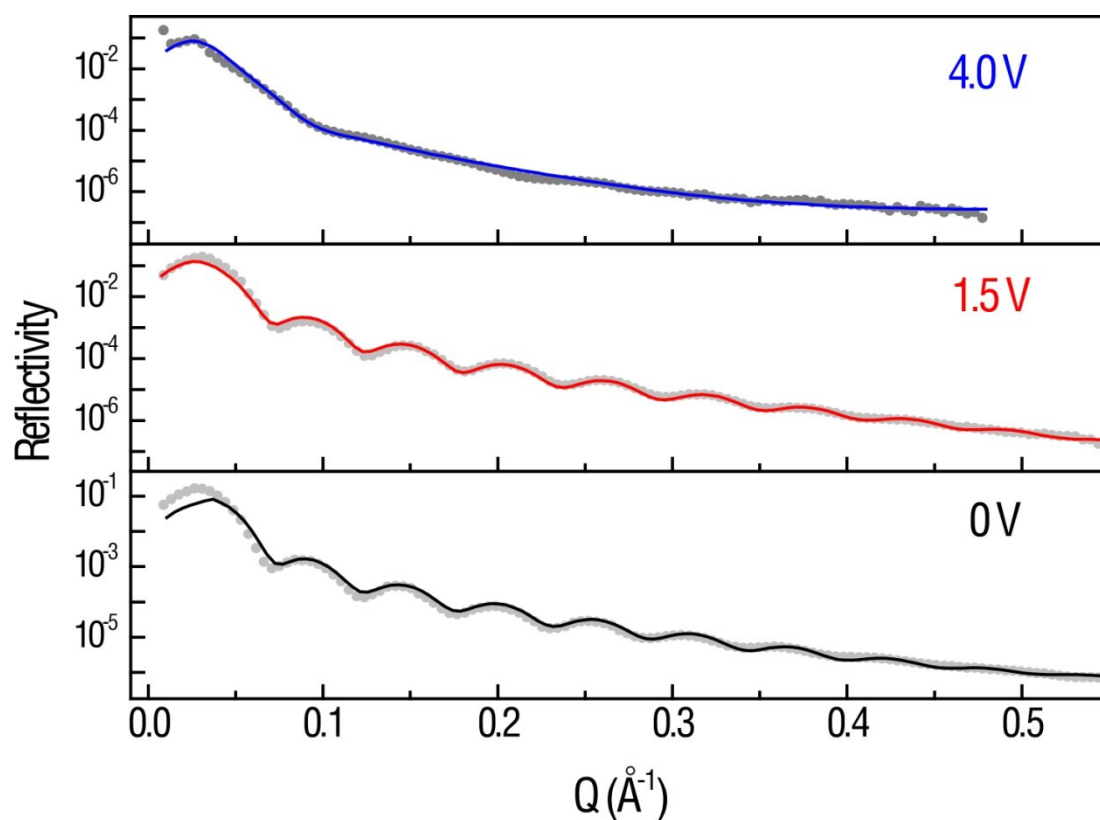


Figure S5 Fitting of the measured XRR profile for different gating voltage

## 6. EELS data processing

Electron energy loss spectroscopy (EELS) is a powerful technique for this study because the valence state of transition metal Fe can be analyzed by measuring the relative intensity of the transition metal  $L_3$  and  $L_2$  lines. The scan range and line scanning images were shown in Figure S6-1 a-d for ungated and 1.5 V gated  $\text{Fe}_3\text{O}_4/\text{MgO}$  heterostructure respectively. In Figure S6e and f, the additional background intensity was removed and  $L_3$  and  $L_2$  values were obtained.

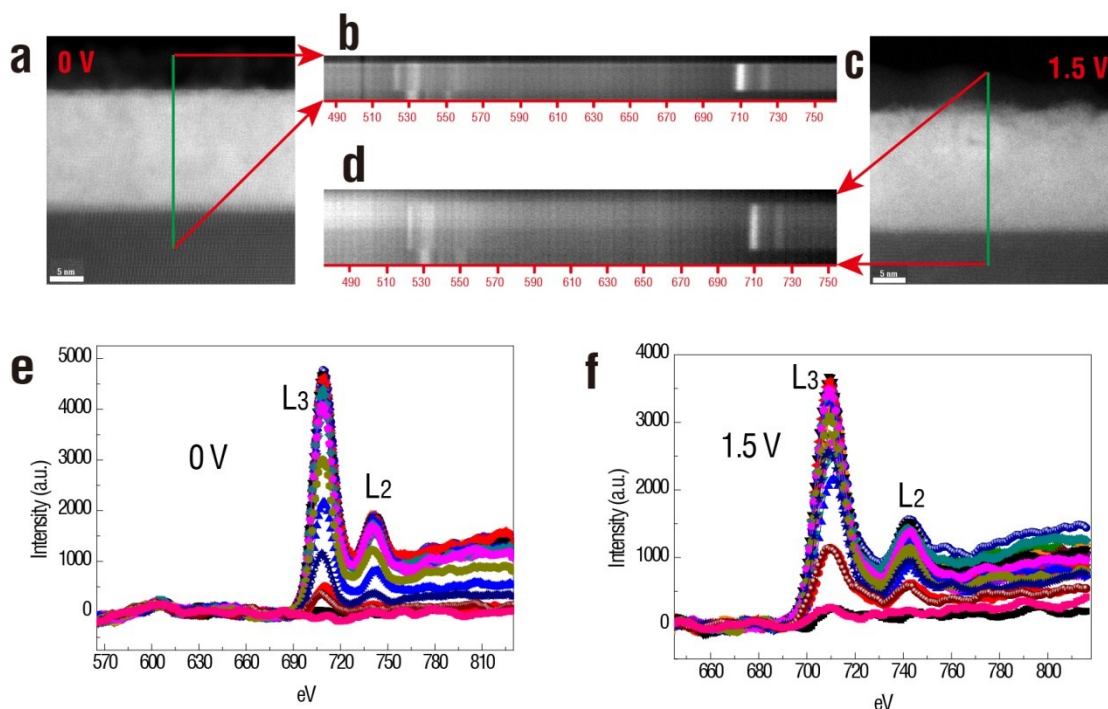


Figure S6-1 (a), (b) and (c), (d) were the scan range and line scanning images for the ungated and 1.5 V gated  $\text{Fe}_3\text{O}_4/\text{MgO}$  heterostructure respectively. (e) and (f) shows the  $L_3$  and  $L_2$  intensity with additional background intensity removed.

The  $L_3/L_2$  intensity ratio as a function of the  $\text{Fe}_3\text{O}_4$  thickness is shown in Figure S6-2 for ungated (blue) and 1.5 V-gated (red) samples. Detailed EELS analysis and data are presented in Figure S6. Within the top 2.5 nm layer of the  $\text{Fe}_3\text{O}_4$  films, the  $L_3/L_2$  ratio of ungated and 1.5 V-gated samples were very different, indicating a significant drop of  $\text{Fe}^{3+}$  near the interface during the gating process. In contrast, the  $L_3/L_2$  ratios of both samples are almost identical inside the  $\text{Fe}_3\text{O}_4$  layer ( $\sim 17.5$  nm), confirming that the IL gating process can only influence the interfacial magnetism of a few nanometers within the chemical window of IL.

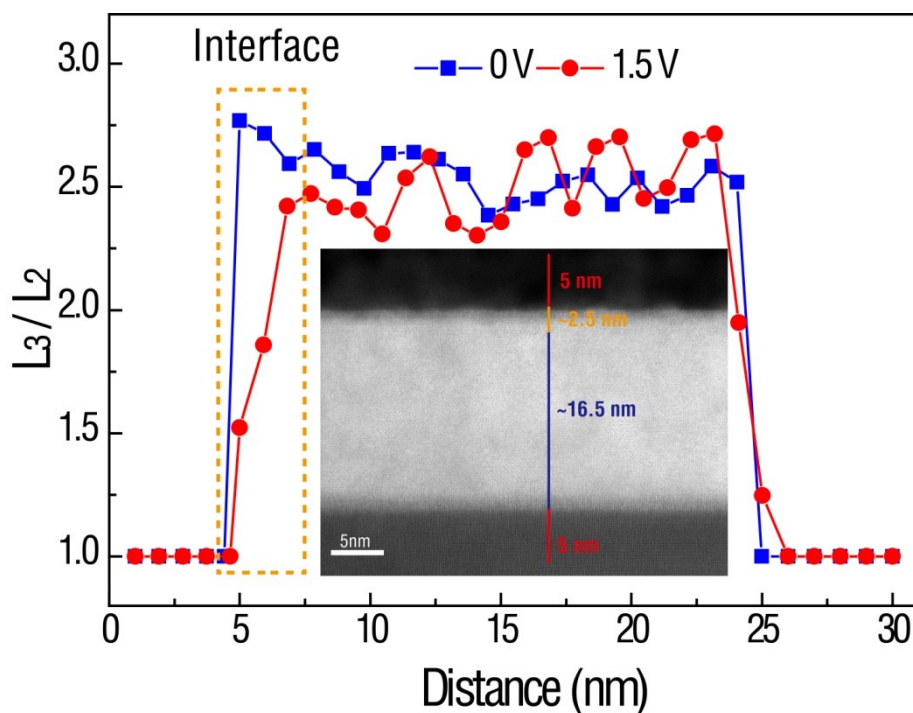


Figure S6-2  $L_3/L_2$  intensity ratio as a function of the measurement range during the EELS analysis for ungated and +1.5 V-gated samples. The inset displays the EELS analysis range: 5 nm glue, 2.5 nm interface, 16.5 nm  $Fe_3O_4$  layers and 5 nm MgO substrates.

## 7. The XPS spectra of O 1s of the heterostructures gated at 0 V, 1.5 V and 4 V

The XPS spectra of O 1s of the heterostructures gated at 0 V, 1.5 V and 4 V are shown in Figure S7 a-c. According to the fitting results, the relative content of O bond with Fe ( $Fe^{2+}$  and  $Fe^{3+}$ ) decrease from 32.35%, to 29.96% and then to 24.8% when gating voltage increase from 0 V to 1.5 V and then 4 V. Also we can get the conclusion by the variation of the ratio of  $Fe^{2+}$  and  $Fe^{3+}$ : during the gating process, parts of  $Fe^{3+}$  transfer to  $Fe^{2+}$ , to balance the valence, some oxygen should be lost and the oxygen vacancies come out.



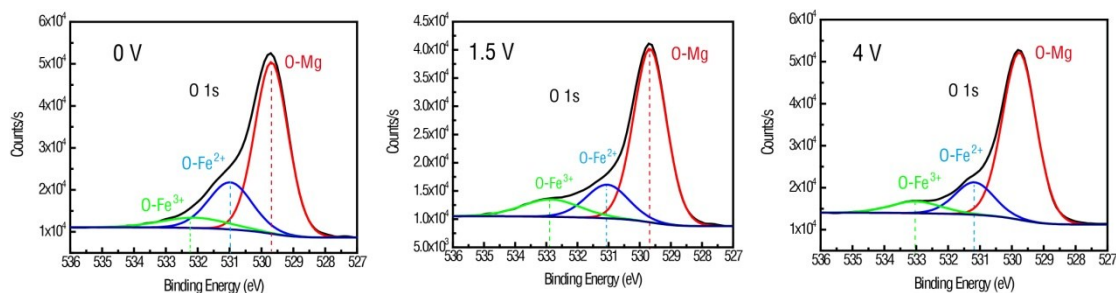


Figure S7 The XPS spectra of O 1s of the heterostructures gated at 0 V, 1.5 V and 4 V

### 8. Surface morphology for the ungated, 1.5 V and 5 V gated samples

The surface roughness change is negligible for both ungated (0.198 nm) and 1.5 V gated (0.177 nm) due to the extreme bits of chemical reactions. For the  $\text{Fe}_3\text{O}_4/\text{MgO}$  heterostructure gated at 5 V in Region II, a drastic roughness increase (0.392 nm) was detected from AFM image in Figure S8(c), which is due to the erosive electrochemical reaction outside the electrochemical window. The existence of destructive chemical reaction here leads to a serious mass loss, significant roughness increasing and an irreversible VCMA.

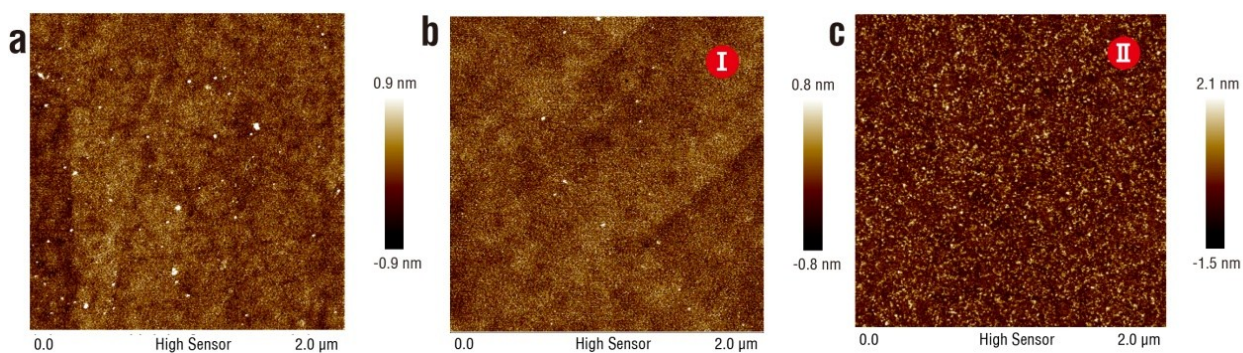


Figure S8 AFM images of ungated, 1.5 V gated and 5 V gated samples